IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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h re Application of:

Suzuki, et al.

Serial No.: 10/004,489

Confirmation No.: 9428

Filed:

October 23, 2001

For:

METHOD OF FORMING FILM,

METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE,

AND FILM FORMING

APPARATUS

Commissioner for Patents Washington, D.C. 20231

Dear Sir:

Group Art Unit: 2818

Examiner:

Berry, Renee

CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on 1/28, 2003 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231.

RESPONSE TO RESTRICTION REQUIREMENT DATED MARCH 26, 2003

In response to the Restriction Requirement dated March 26, 2003, having a shortened statutory period for response set to expire on April 28, 2003, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicants believe that no fee is due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/3819/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

IN THE SPECIFICATION:

Please replace the specification with the attached substitute specification. A marked-up copy of the specification is also attached.